

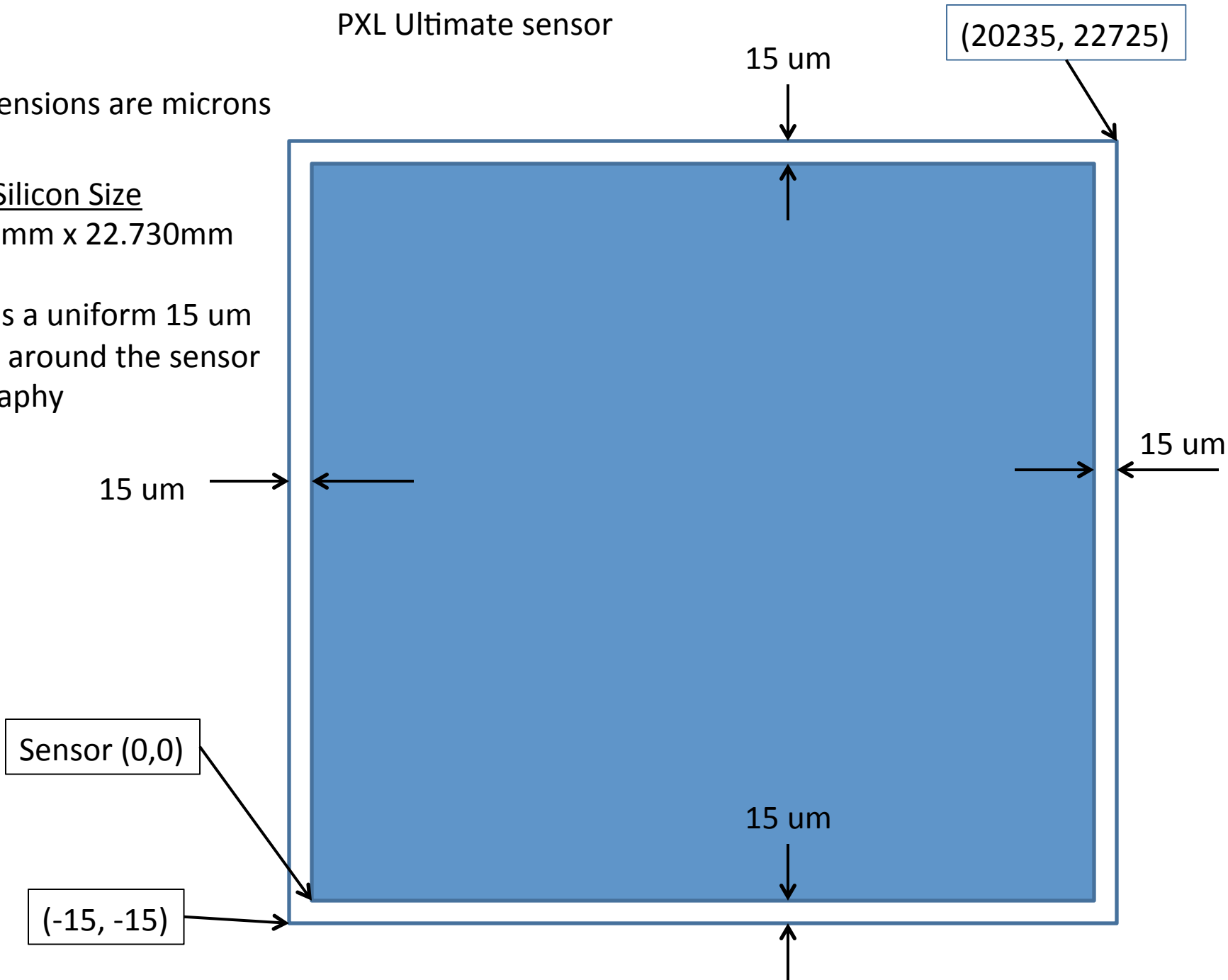
PXL Ultimate sensor

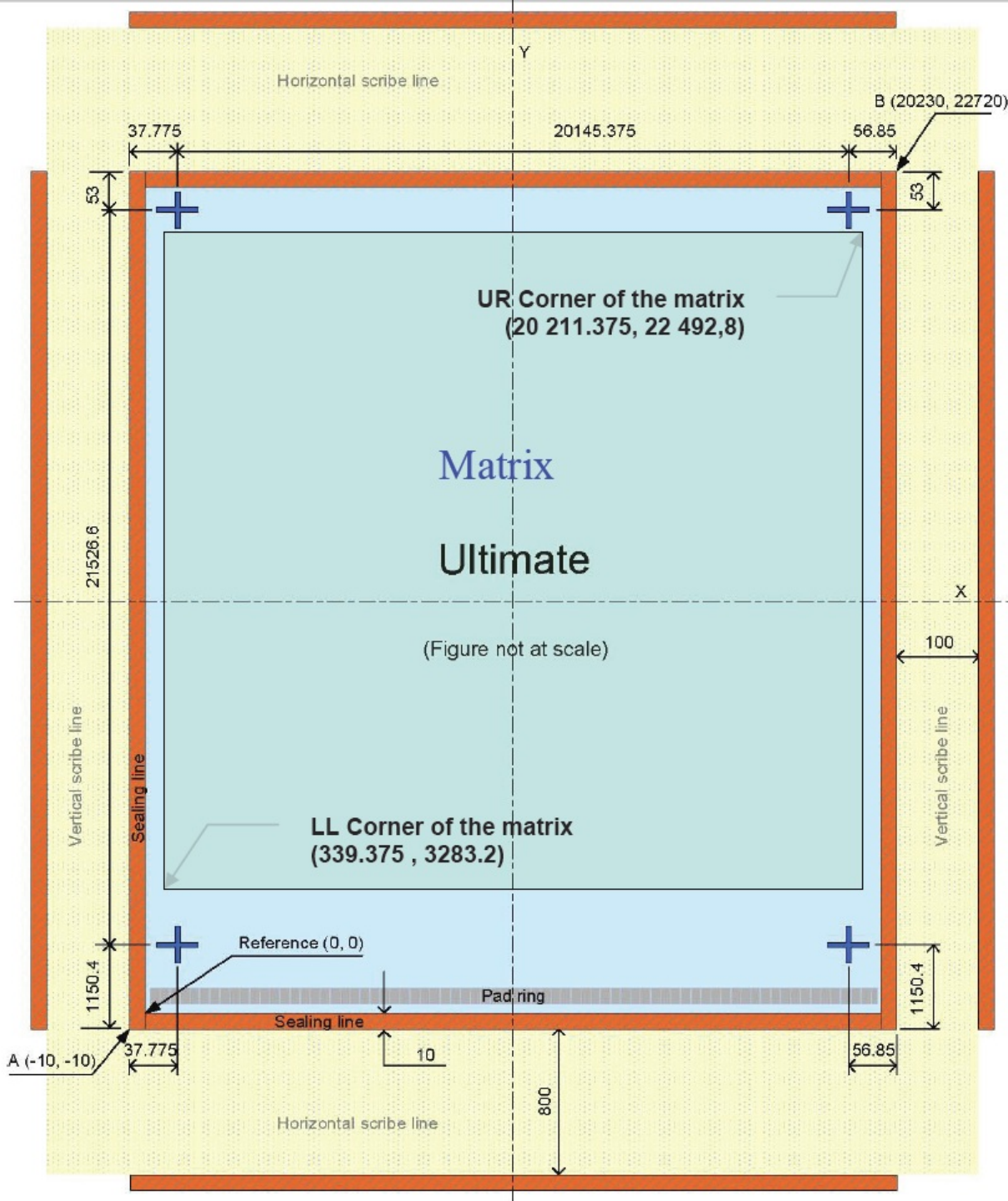
Dimensions are microns

Diced Silicon Size

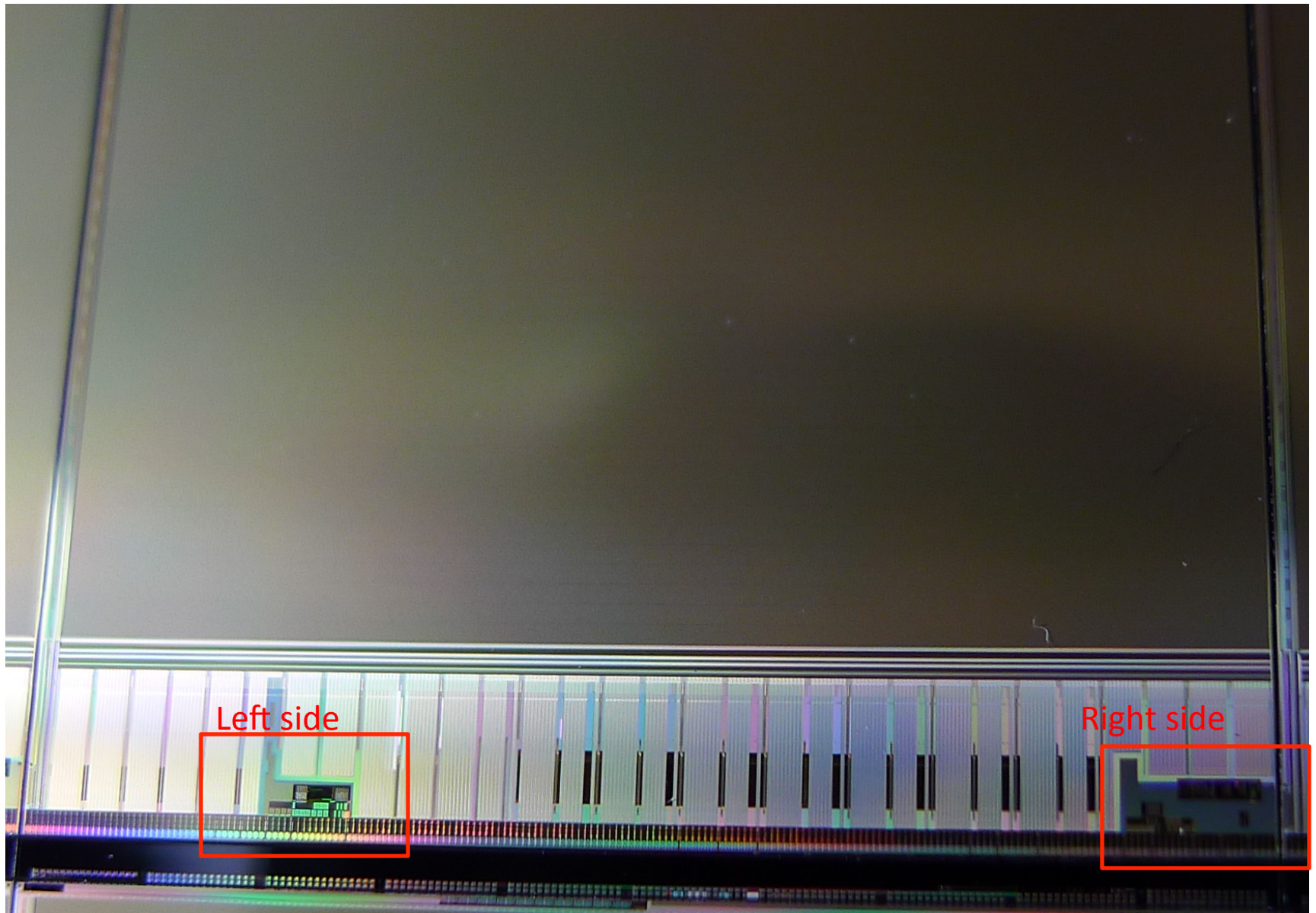
20.240mm x 22.730mm

There is a uniform 15 μm border around the sensor lithography





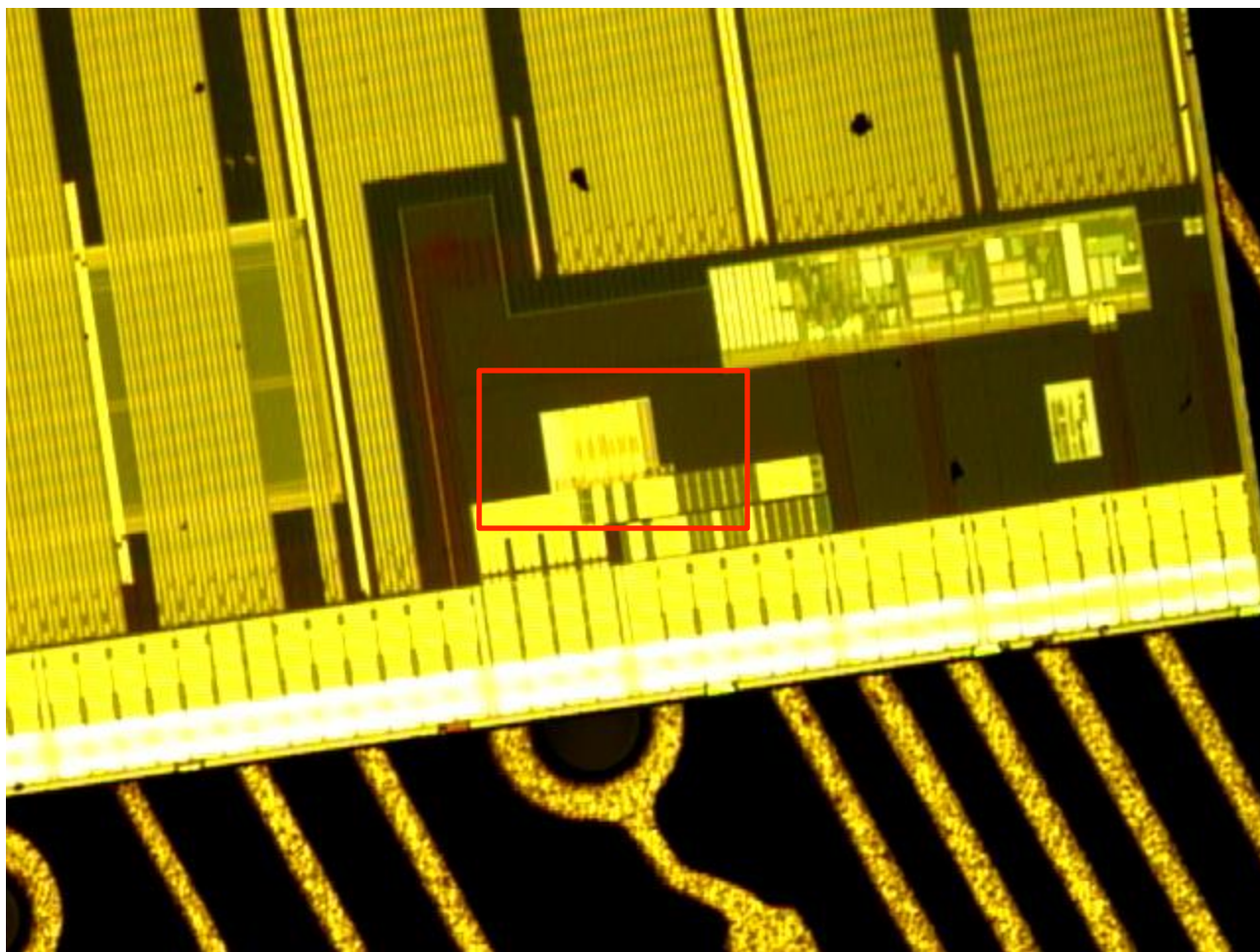
- Optical fiducial point locations are shown on the next pages



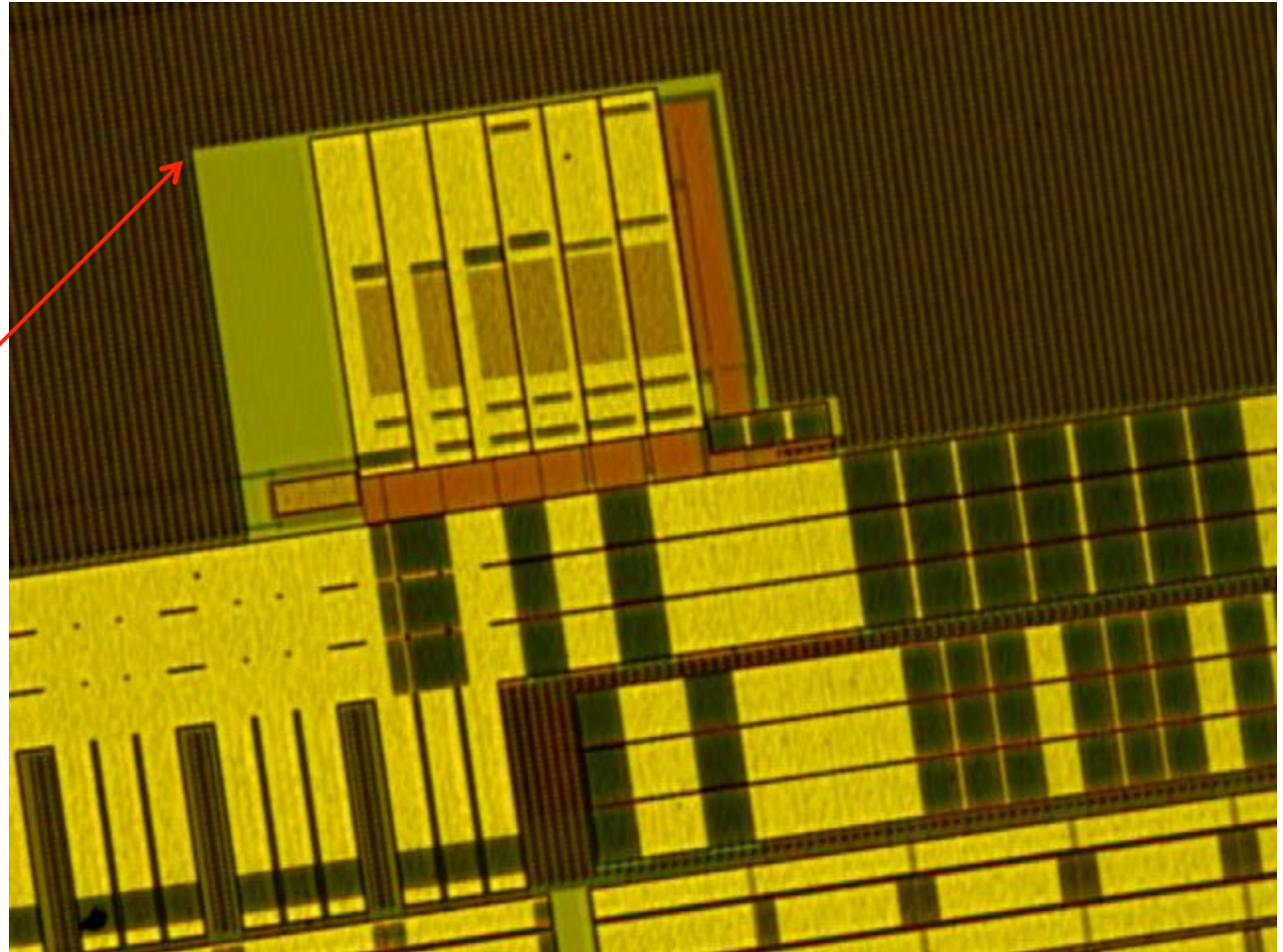
Left side

Right side

Right Side



Right Side

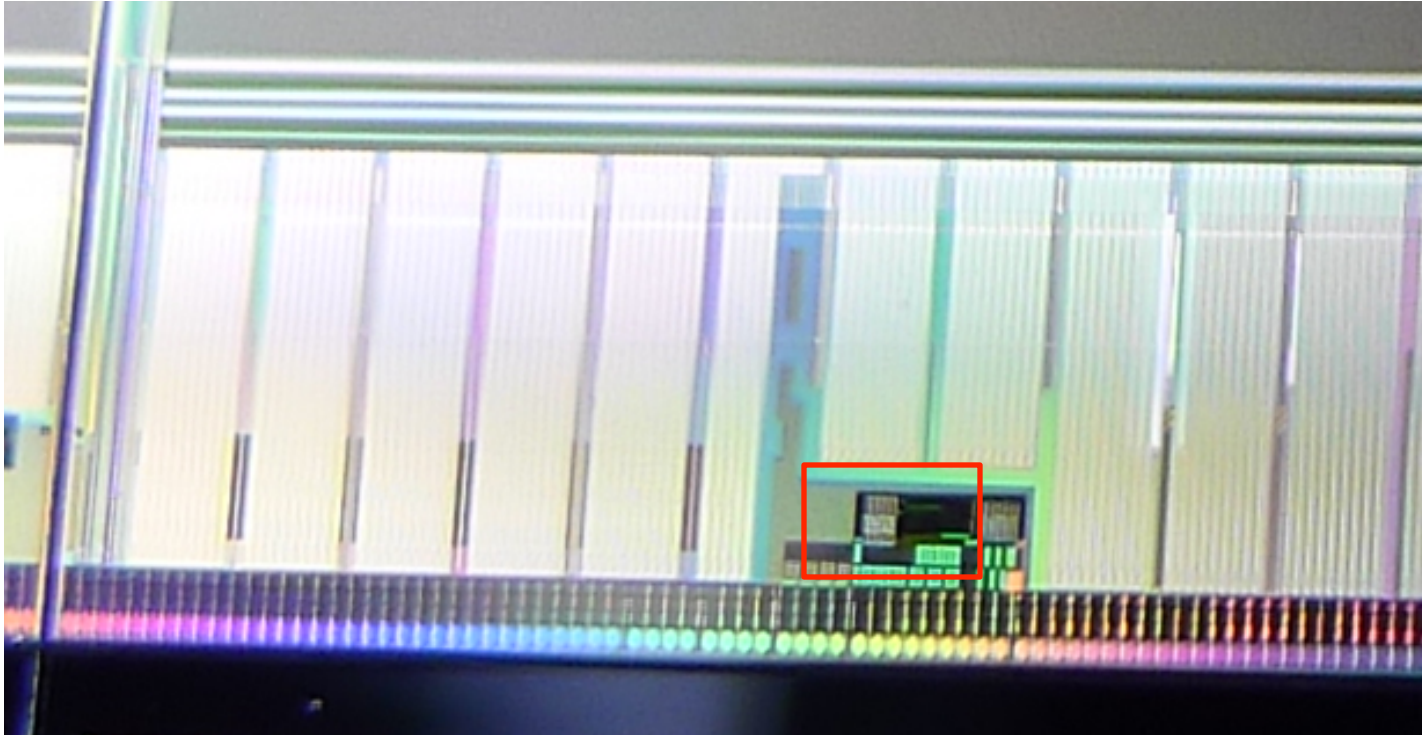


This corner

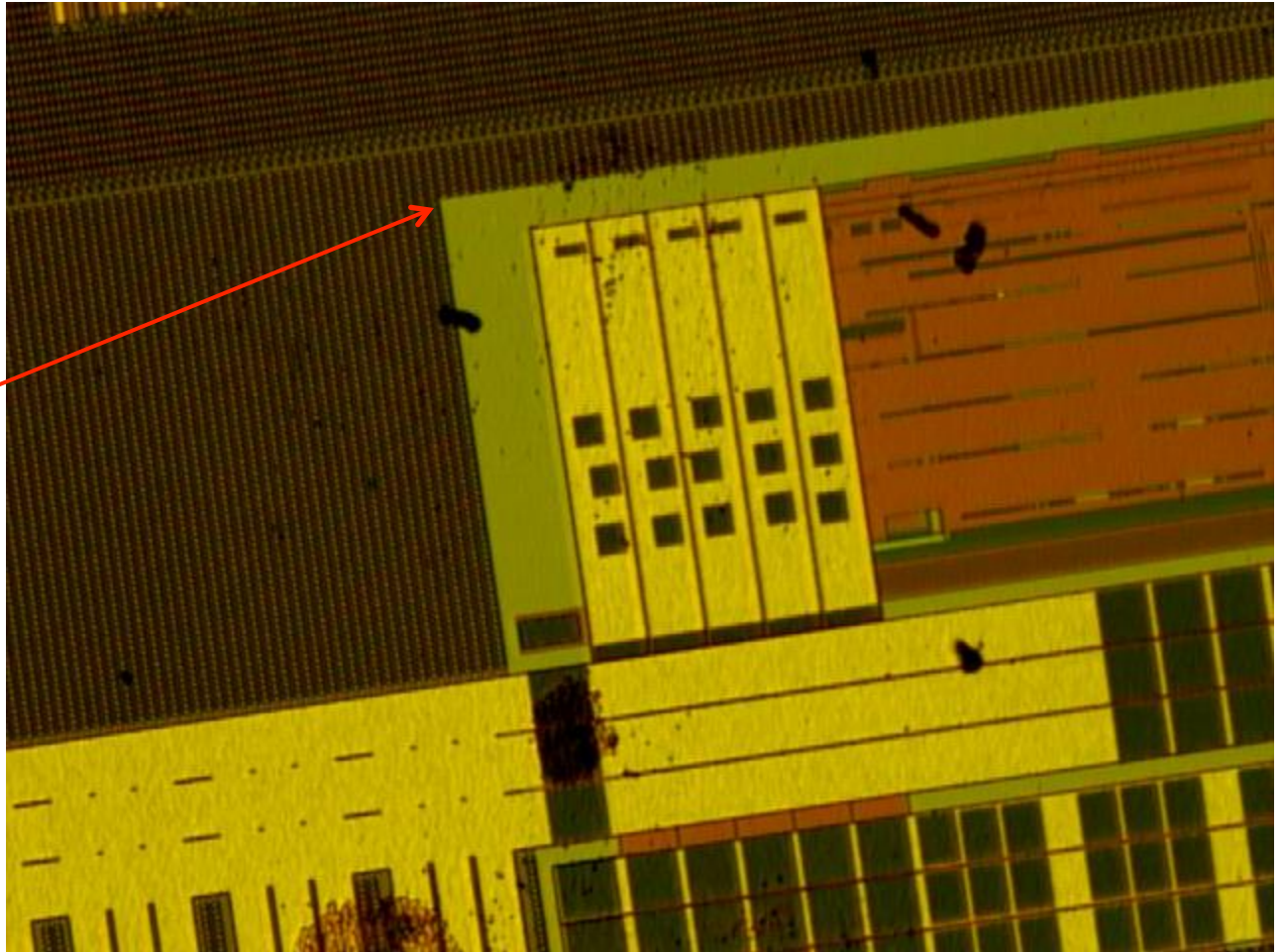
X= 18165.075 μm

Y= 871.6 μm

Left Side



Left Side

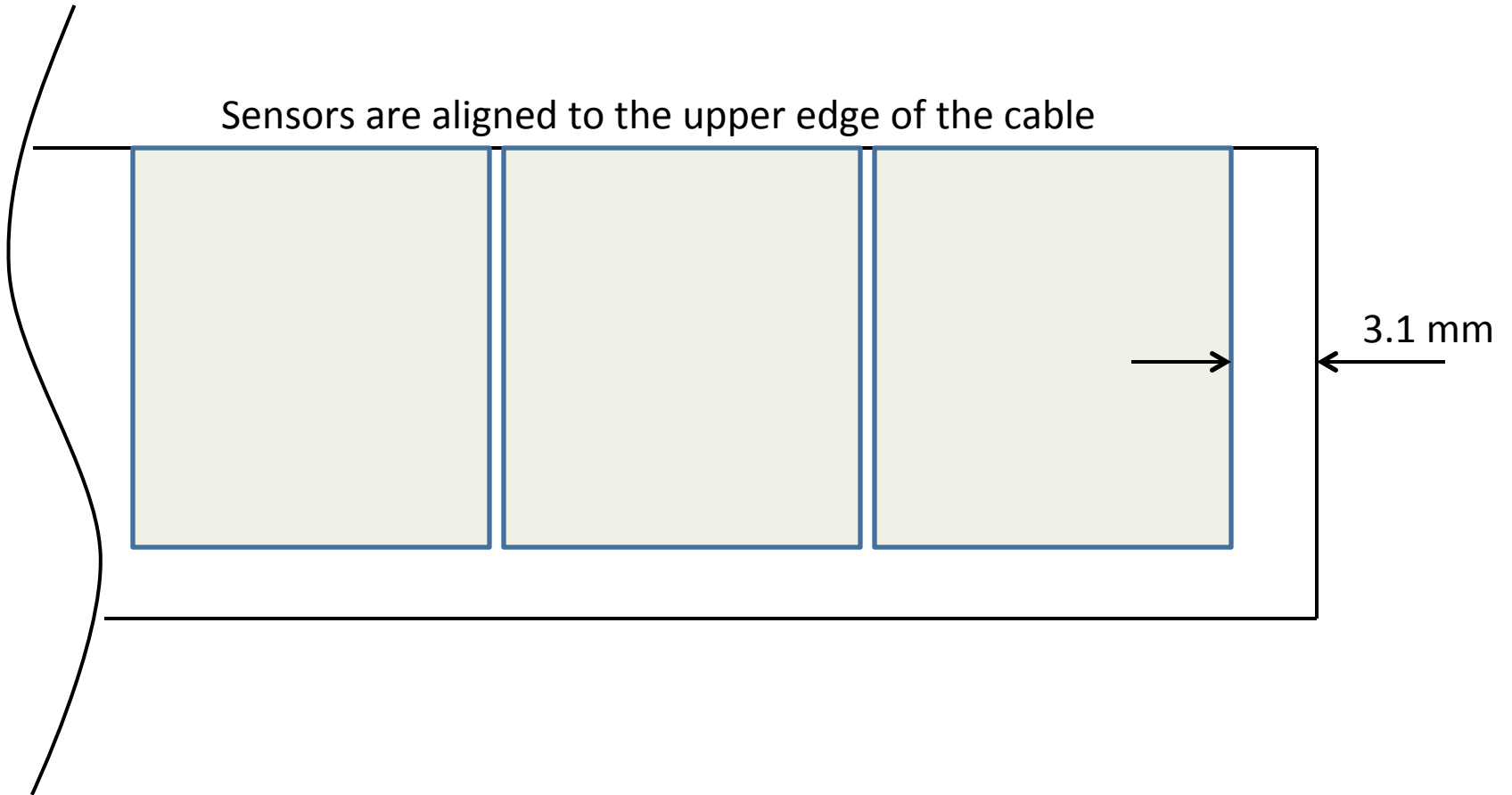


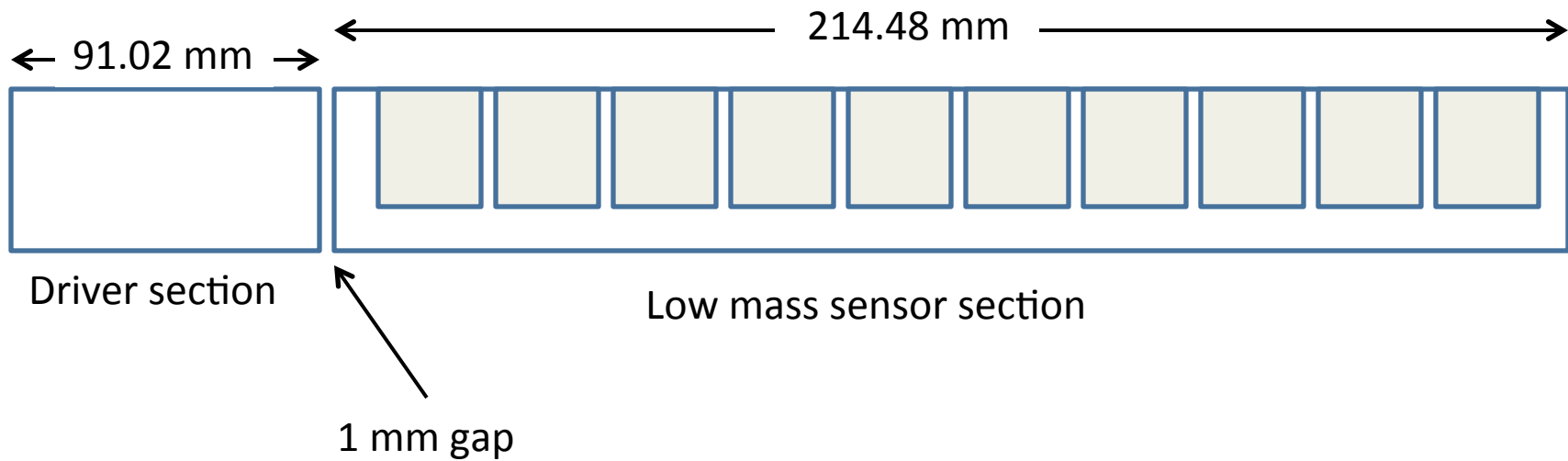
This corner
X= 4594.225 μm
Y= 920.775 μm

- Cable sizes and locations of sensors

Ladder end detail

Sensors are aligned to the upper edge of the cable





Total length = 306.5 mm
Width = 24.43 mm

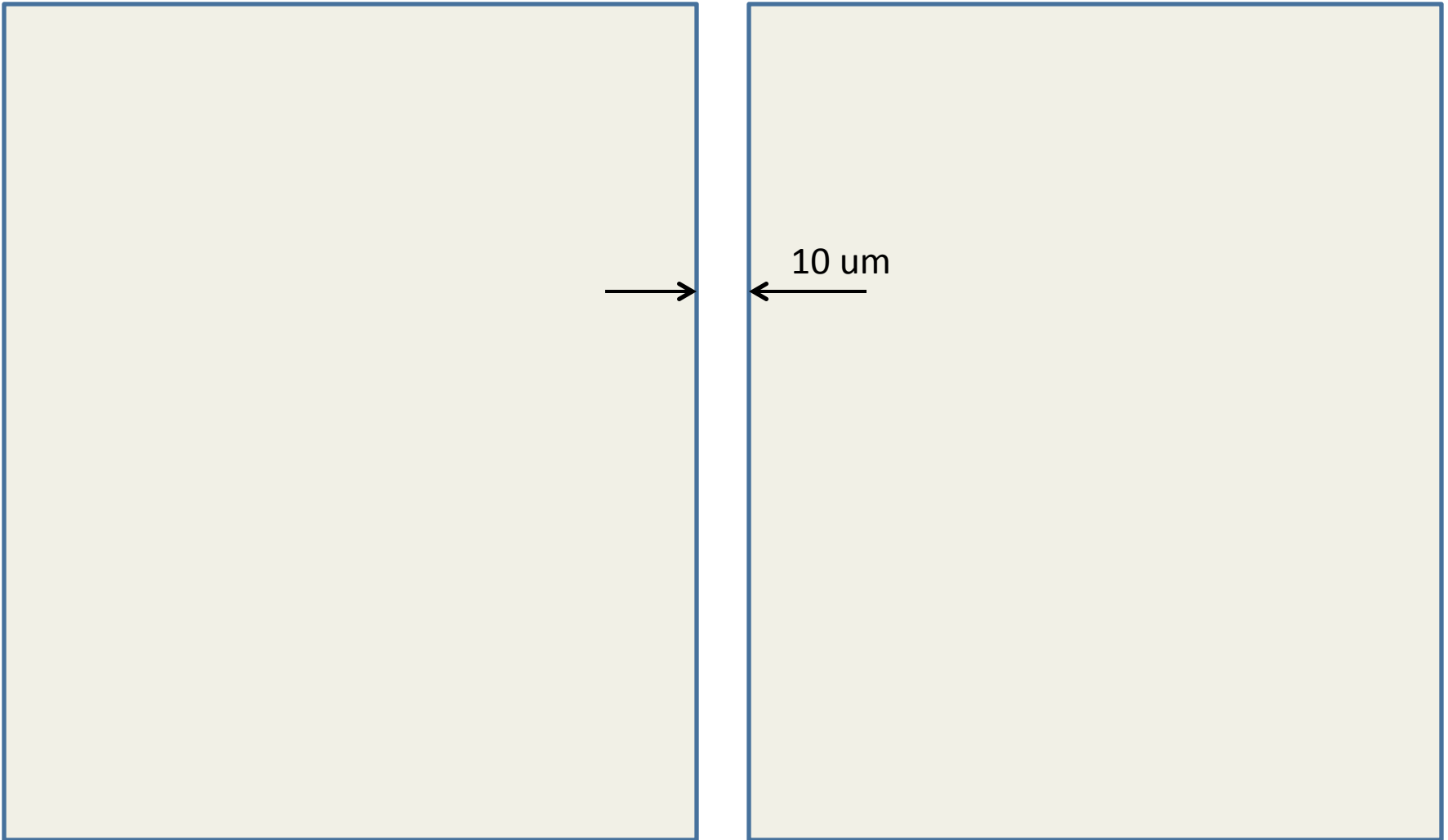
Joe Silber - Attached are measurements I made yesterday.

- 1) If I divide the total width of 10 butted sensors by 10x Leo's nominal width (19.62mm) I get an average gap of 2um.
- 2) If I instead divide by the width I measured (19.607mm) then I get average gap of 16um.
- 3) If I add up the worst cases of offset and rotation that I measured, then the maximum tol envelope would be 54um.
- 4) If I add up the stdevs on offset and rotation that I measured, then the tol envelope should be 18um.

Clearly I may be simply interpreting the edge of sensor incorrectly due to my lighting conditions. If so, then the average gap is tiny, 2um, as in case (1). But if I am seeing things correctly on the smartscope, then this batch of sensors were cut undersized by about 13um on average, and the correct gap to model would be more like 16-18um, as in cases (2) and (4). Case (3) is essentially what Howard originally assumed (2 mil), but in reality it looks to me like it would be incorrect for us to assume this worst-case placement on every sensor.

I think the bottom line is that if Leo can stomach about 100um maximum error for wire bond alignment, then we should be fine splitting the difference between the 2 um and 18 um numbers, **and calling the nominal gap 10um.**

Gap detail

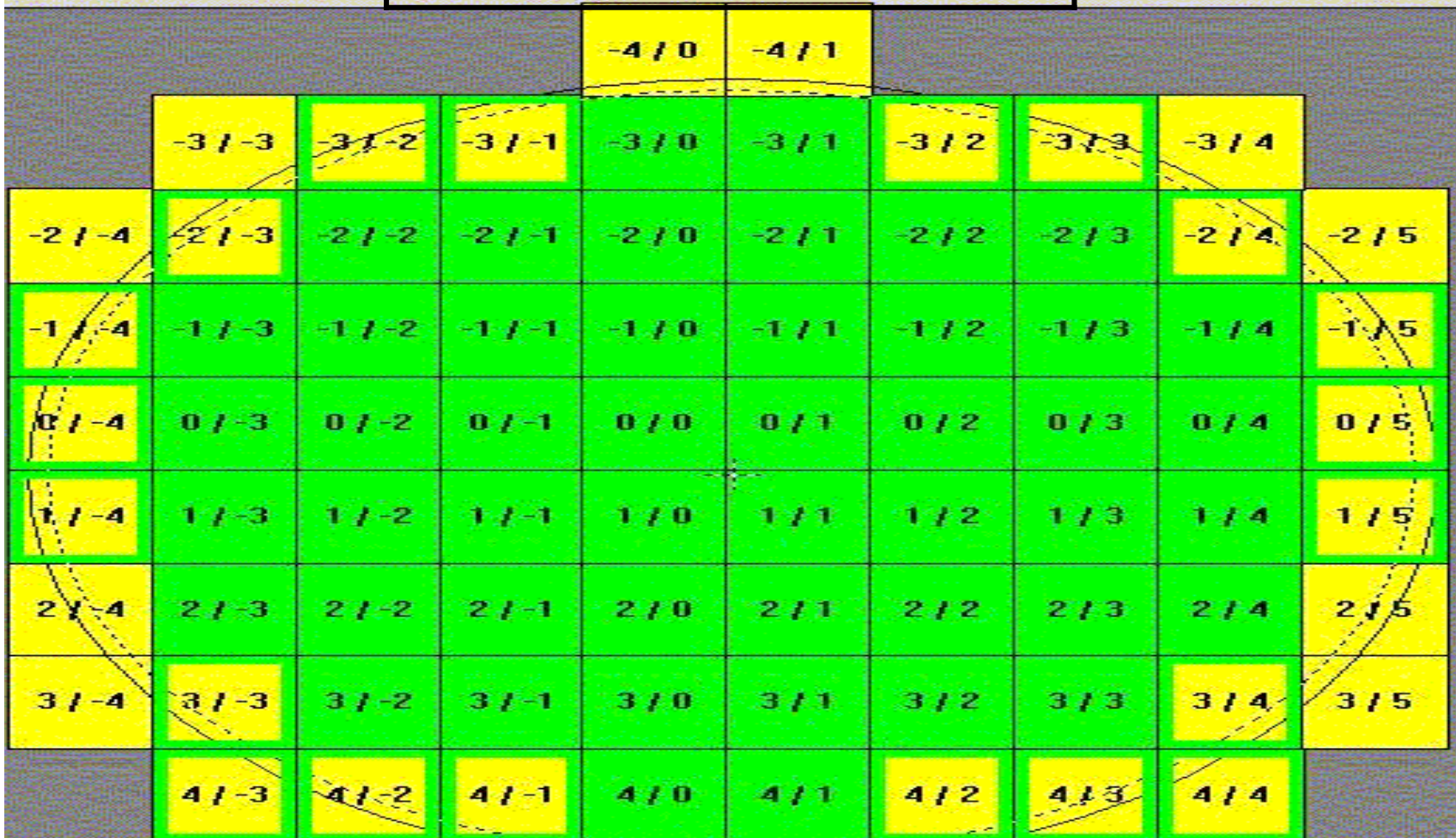


- More background material

ULTIMATE

Run SA35C11_1 # 12404

	X (mm)	Y (mm)
Chip Size	20,240	22,730
Step Size	20,340	23,530
Scribeline	0,100	0,800
Possible Dies 48		



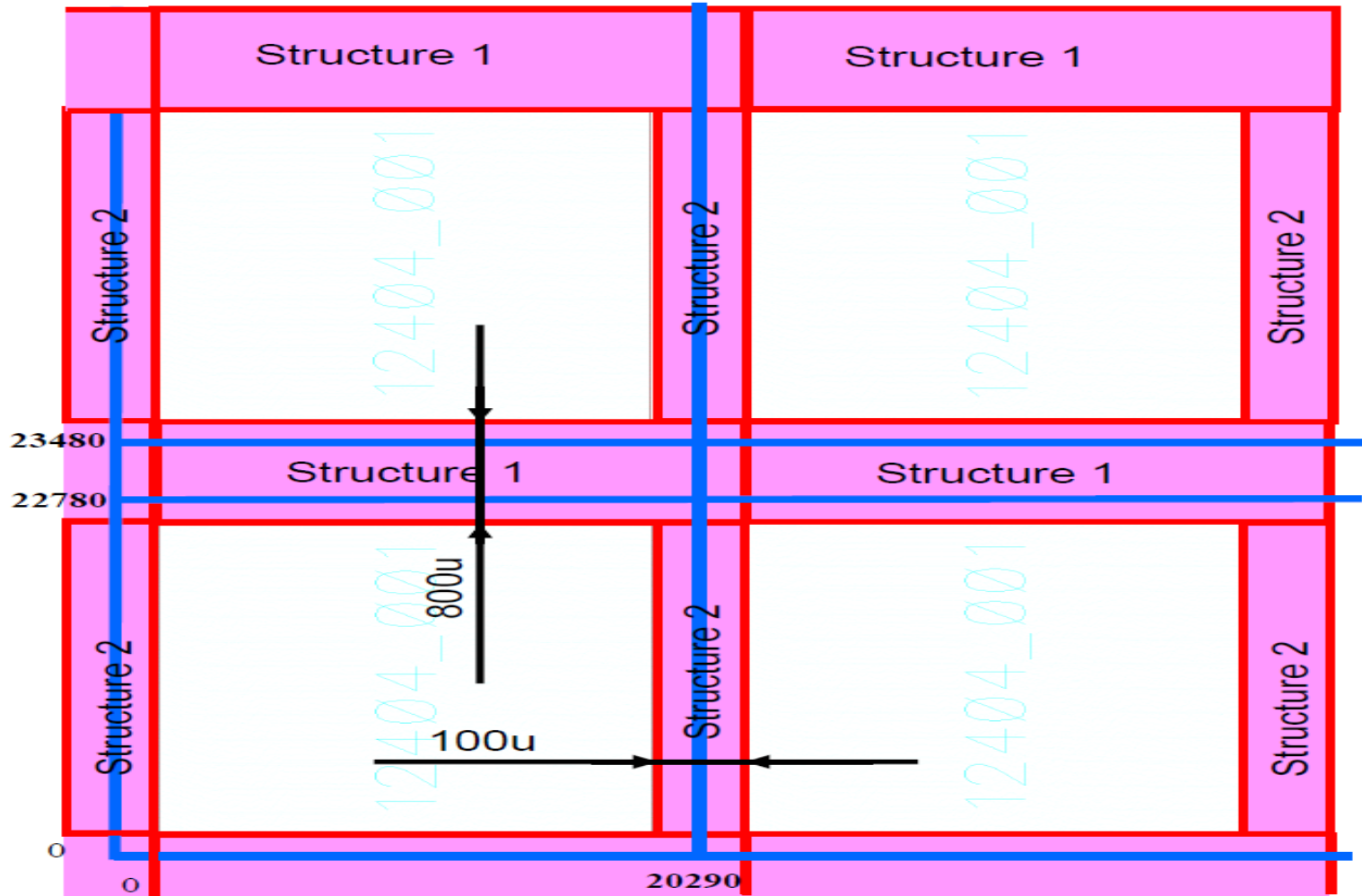
Traceability – Chip Numbering

				-4 / 0	-4 / 1								
				-3 / -3	-3 / -2	-3 / -1	A01	A02	-3 / 2	-3 / 3	-3 / 4		
-2 / -4	-2 / -3	B01	B02	B03	B04	B05	B06	-2 / 4	-2 / 5				
-1 / -4	C01	C02	C03	C04	C05	C06	C07	C08	-1 / 5				
0 / -4	D01	D02	D03	D04	D05	D06	D07	D08	0 / 5				
1 / -4	E01	E02	E03	E04	E05	E06	E07	E08	1 / 5				
2 / -4	F01	F02	F03	F04	F05	F06	F07	F08	2 / 5				
3 / -4	3 / -3	G01	G02	G03	G04	G05	G06	3 / 4	3 / 5				
				4 / -3	4 / -2	4 / -1	H01	H02	4 / 2	4 / 3	4 / 4		

Sawing Diagram

Version: March 2nd, 2011

SA35C11_1 # 12404



— Sawing line

	X (mm)	Y (mm)
Chip Size	20,240	22,730
Step Size	20,340	23,530
Scribeline	0,100	0,800
Possible Dies	48	

Sawing diagram
WAFER n° 5 :
Nbr. de wafer: 1
SA35C11_1 # 12404